



<https://www.desy.de/>

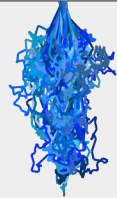
0.5ns



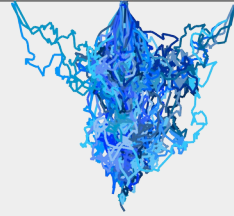
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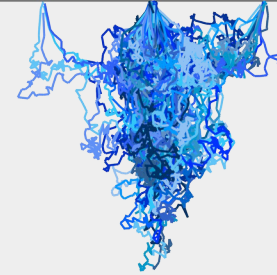
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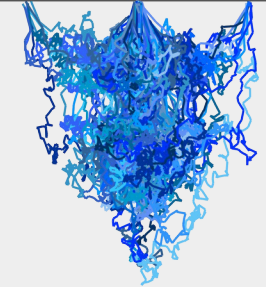
15ns



20ns



25ns



Ongoing & Future Developments of the Allpix Squared Framework

Simon Spannagel, DESY

3rd Allpix Squared User Workshop

11 May 2022

Virtual

Upcoming Release: Allpix Squared 2.3

- Release most likely next week already
- Paul presented most features on Monday:
 - Support for different Semiconductor Sensor Materials
 - Mobility model “constant”
 - Temperature scaling of SRH recombination
 - Charge carrier trapping from radiation-induced damage, different models

- Subsequent release very likely v3.0 with...

Impact Ionization

Implementation of charge multiplication through impact ionization underway

- Multiple models available, selection via configuration file:
 - Massey
 - van Overstraeten-de Man
 - Okuto-Crowell
 - Bologna
- Fully documented in user manual
- **Implementation in Allpix² completed**, undergoing testing, Comparison with Weightfield2 & TCAD simulations

coefficient α and the length of the step l performed in the respective electric field. If the electric field strength stays below a configurable threshold E_{thr} , unity gain is assumed:

$$g(E, T) = \begin{cases} e^{l \cdot \alpha(E, T)} & E > E_{\text{thr}} \\ 1.0 & E < E_{\text{thr}} \end{cases} \quad (6.12)$$

The the following impact ionization models are available:

6.3.1 Massey Model

The Massey model [35] describes impact ionization as a function of the electric field E . The ionization coefficients are parametrized as

$$\alpha(E, T) = A e^{-\frac{B(T)}{E}}, \quad (6.13)$$

where A and $B(T)$ are phenomenological parameters, defined for electrons and holes respectively. While A is assumed to be temperature-independent, parameter B exhibits a temperature dependence and is defined as

$$B(T) = C + D \cdot T. \quad (6.14)$$

The parameter values implemented in Allpix² are taken from Section 3 of [35] as:

$$\begin{aligned} A_e &= 4.43 \times 10^5 / \text{cm} & A_h &= 1.13 \times 10^6 / \text{cm} \\ C_e &= 9.66 \times 10^5 \text{ V/cm} & C_h &= 1.71 \times 10^6 \text{ V/cm} \\ D_e &= 4.99 \times 10^2 \text{ V/cm/K} & D_h &= 1.09 \times 10^3 \text{ V/cm/K} \end{aligned}$$

for electrons and holes, respectively.

This model can be selected in the configuration file via the parameter `multiplication_model = "massey"`.

6.3.2 Van Overstraeten-De Man Model

The Van Overstraeten-De Man model [36] describes impact ionization using Chynoweth's law, given by

$$\alpha(E, T) = \gamma(T) \cdot a_{\infty} \cdot e^{-\frac{\gamma(T) \cdot b}{E}}, \quad (6.15)$$

For holes, two sets of impact ionization parameters $p = \{a_{\infty}, b\}$ are used depending on the electric field:

$$p = \begin{cases} p_{\text{low}} & E < E_0 \\ p_{\text{high}} & E > E_0 \end{cases} \quad (6.16)$$

Temperature scaling of the ionization coefficient is performed via the $\gamma(T)$ parameter following the Synopsys Sentaurus TCAD user manual as:

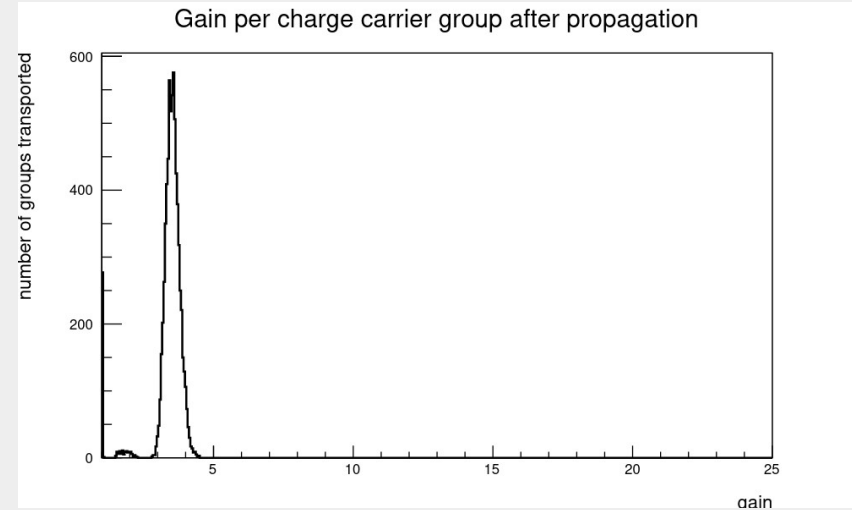
$$\gamma(T) = \tanh\left(\frac{0.063 \times 10^6 \text{ eV}}{28.6173 \times 10^{-5} \text{ eV/K} \cdot T_0}\right) \cdot \tanh\left(\frac{0.063 \times 10^6 \text{ eV}}{28.6173 \times 10^{-5} \text{ eV/K} \cdot T}\right)^{-1} \quad (6.17)$$

Impact Ionization – Example



- Enable/select via configuration file:
 - Multiplication model
 - Electric field strength threshold field for multiplication

```
[GenericPropagation]
temperature = 293K
multiplication_model = "massey"
multiplication_threshold = 100kV/cm
```



- Automatic check of propagation parameters (time stepping, ...)

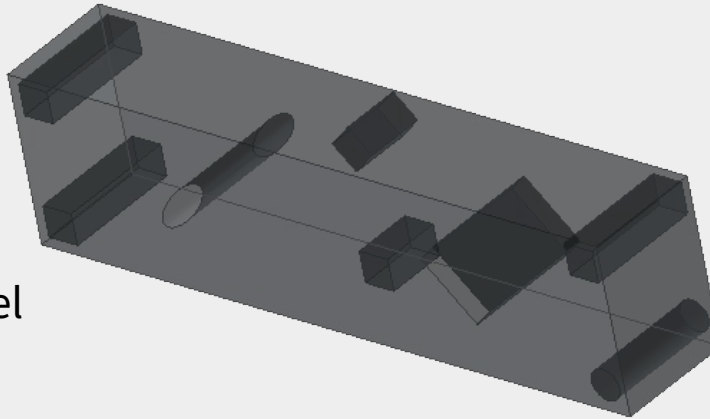
```
(WARNING) [I:GenericPropagation:lgad] Charge multiplication enabled with maximum timestep larger than 1ps
This might lead to unphysical gain values.
```

- Status [MR !472](#)



Simulation of 3D Sensors

- Definition of per-pixel implants via detector model file
 - Position with respect to pixel center
 - Shape & orientation
 - Material
 - front/backside
- Implants are repeated for each pixel
- Add as many implants as required, syntax similar to support layers (PCB etc)
- Requires matching electric field map
- Proper collision detection algorithms of charge carriers with implant volumes; motion stops immediately at implant border



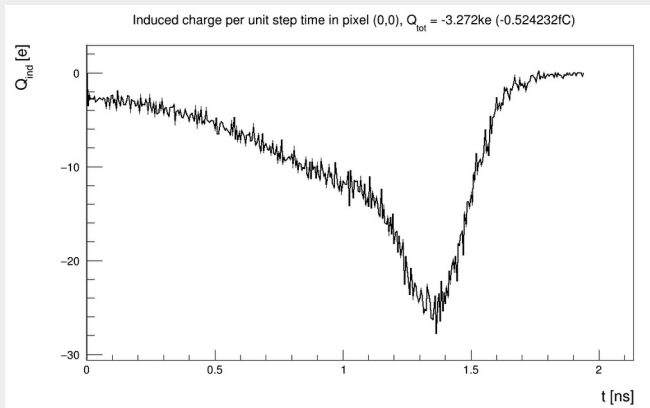
```
1 type = "monolithic"
2
3 number_of_pixels = 20 20
4 pixel_size = 250um 50um
5
6 sensor_thickness = 50um
7 sensor_excess = 10um
8
9 [implant]
10 type = frontside
11 shape = ellipse
12 size = 13um 13um 50um
13 offset = 62.5um 0
14 material = silicon
15
16 [implant]
17 type = frontside
18 shape = ellipse
19 size = 13um 13um 50um
20 offset = -62.5um 0
21 material = silicon
22
23 [implant]
24 type = backside
25 shape = ellipse
26 size = 13um 13um 49um
27 offset = -125um -25um
28 material = aluminum
29
```

Simulation of 3D Sensors – Example

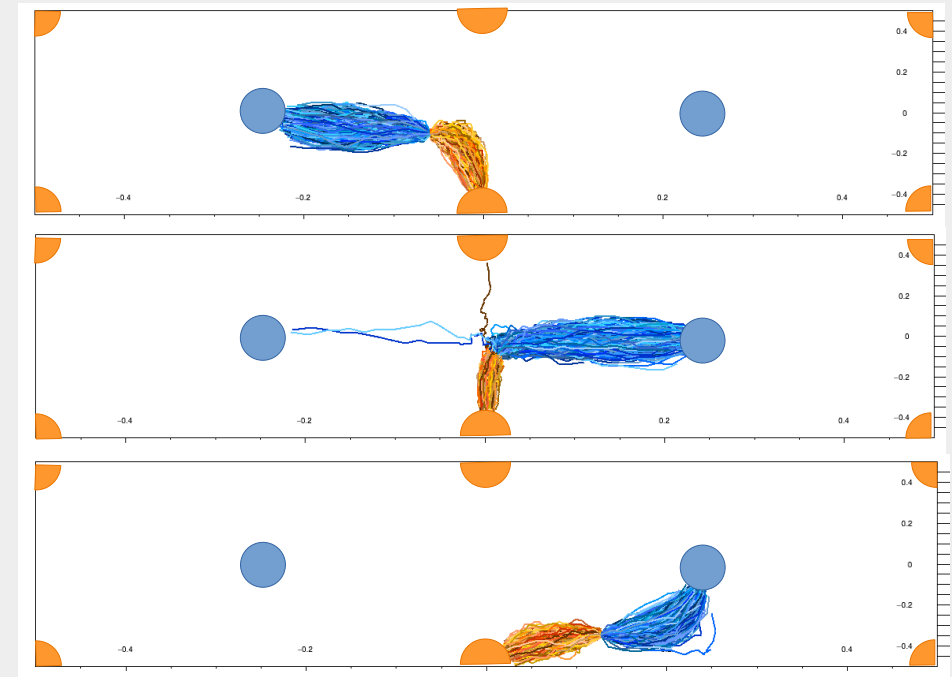
Marco Bomben, Gilberto Giuliarelli,
Gian-Franco Dalla Betta, Simon Spannagel



- First simulations with ATLAS 3D sensor geometry
 - Two central front-side columns (collect charge)
 - Six Ohmic backside contact columns
- Charge collection / sharing works as expected
- Transient simulations produce pulses
- Status: [MR !672](#)



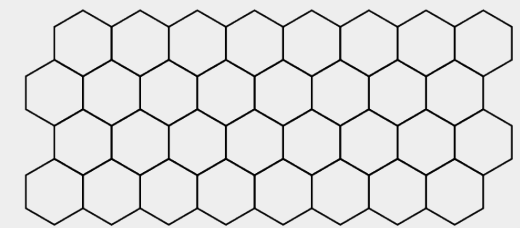
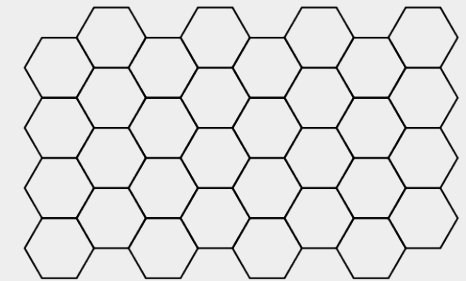
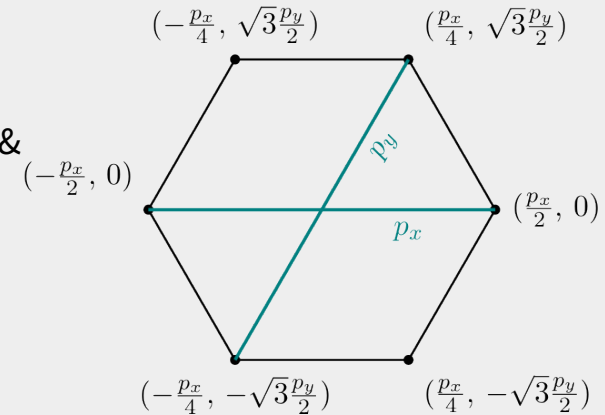
single pixel,
top view



Hexagonal Pixel Geometries

Extension of Allpix² geometry subsystem to enable simulation of different pixel shapes & matrix arrangements

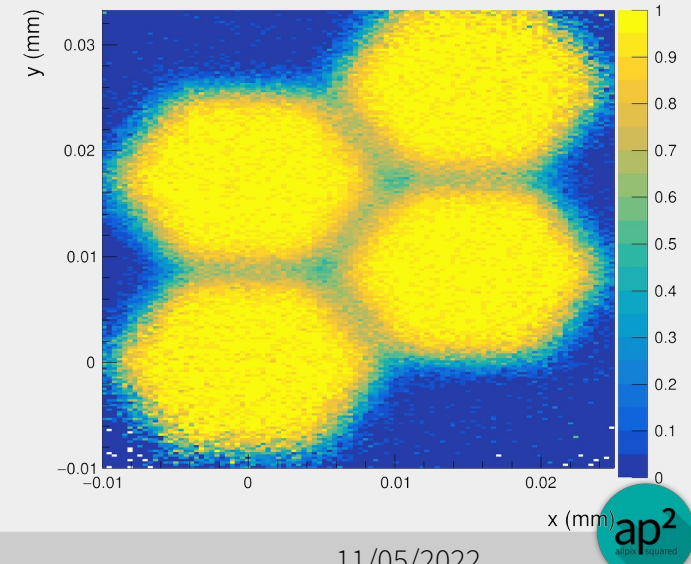
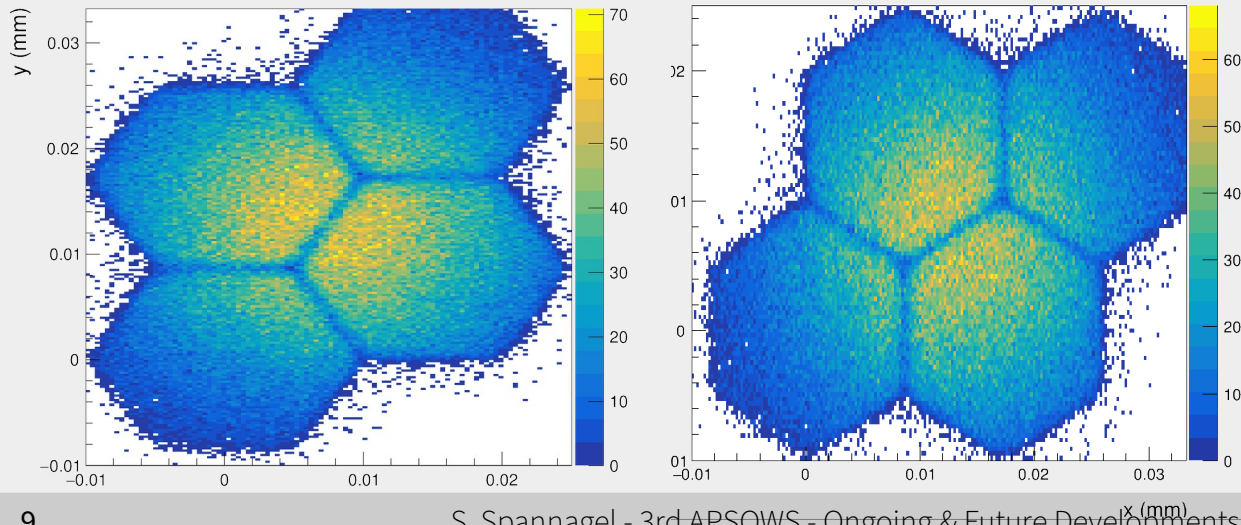
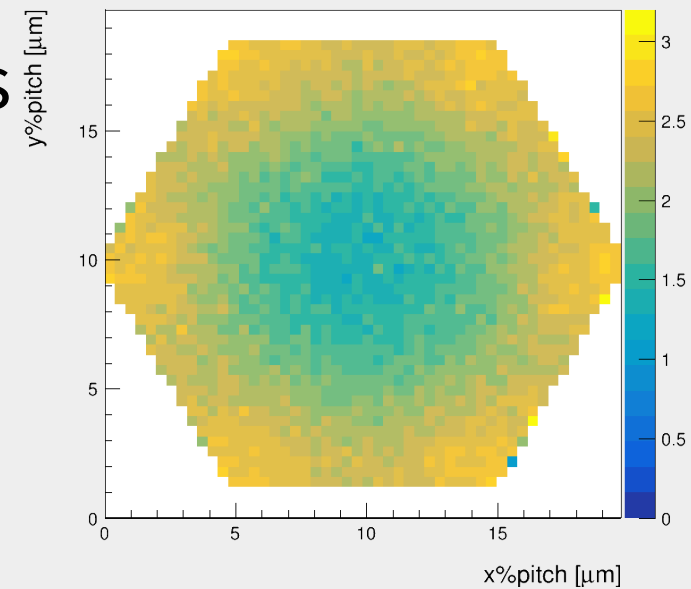
- Hexagonal geometry interesting for many applications
 - Avoid problematic field regions in corners
(small electrodes: low fields, large electrodes: high fields)
 - Symmetry more close to circle – more uniform response
- **Implementation in Allpix² completed**, undergoing testing:
 - Using **axial coordinate system**
 - Support for “pointy” & “flat” hexagon orientation, regular (same-pitch) and distorted (different pitch) hexagons
- Used already by several groups
(see [Raffaella’s talk on FASER](#), [Paco’s talk on Ge-Detector](#))



Other geometries already merged (e.g. radial strips @ ATLAS Itk, see Radek’s talks)

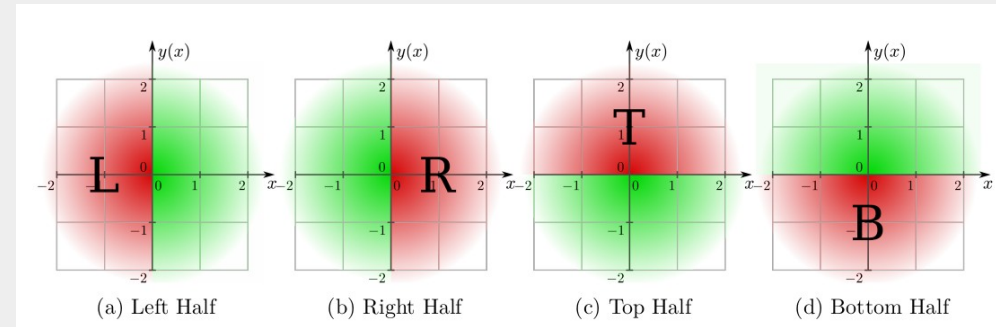
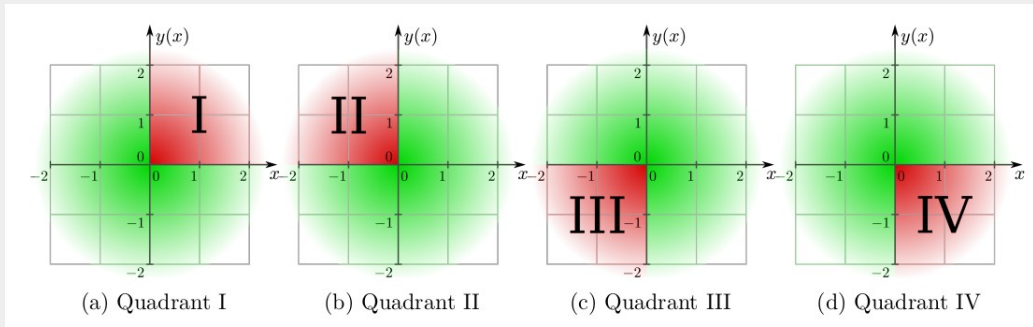
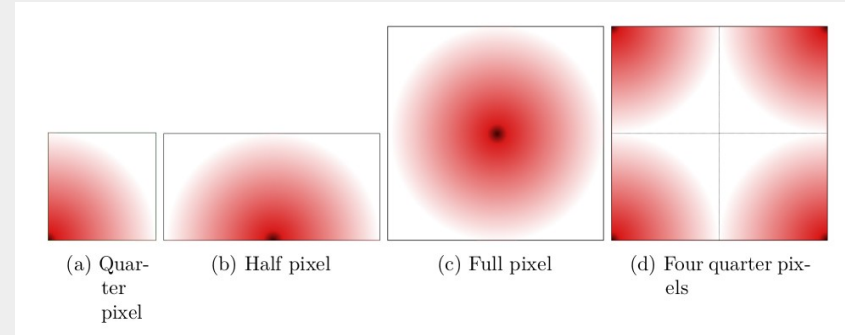
Some Nice Plots – with Hexagonal Pixels

- Performed implementation tests with hexagonal pixel detector
large pixels, linear electric field, high charge threshold
- Analysis of basic properties
 - Recovery of radial beam profile from pixel matrix
 - In-pixel cluster size distribution
 - Efficiency fall-off at hexagon edges



Rework Loading Electric Field Maps

- Current loading of field maps is very flexible...
...but only works for rectangular geometries!
- Started implementation of new mapping of fields to pixels
per-pixel lookup of fields
- Has some advantages (lookup possible for any pixel shape)
and some disadvantages (not possible to provide multi-pixel fields)
- Final solution likely will keep current mapping (as default)
with new possibility (full, half, quarter pixels)



End of the Workshop... almost

Thank you for participating again!

Discussion

- Wishes, ideas, suggestions, questions, ...
- “Things we should have on our radar”

Questionnaire

- We would like to get some feedback!
- On the workshop, the framework, our support, ...
- Please fill the survey on Indico:
<https://indico.cern.ch/event/1126306/surveys/3180>

Allpix Squared Resources



Website

<https://cern.ch/allpix-squared>



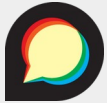
Repository

<https://gitlab.cern.ch/allpix-squared/allpix-squared>



Docker Images

https://gitlab.cern.ch/allpix-squared/allpix-squared/container_registry



User Forum:

<https://cern.ch/allpix-squared-forum/>



Mailing Lists:

allpix-squared-users <https://e-groups.cern.ch/e-groups/Egroup.do?egroupId=10262858>

allpix-squared-developers <https://e-groups.cern.ch/e-groups/Egroup.do?egroupId=10273730>



User Manual:

<https://cern.ch/allpix-squared/usermanual/allpix-manual.pdf>

